## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Hirofumi WATATANI

Serial Number: Not Yet Assigned

Filed: October 16, 2003 Customer No.: 38834

For: MICRO PATTERN FORMING METHOD AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD

## INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

October 16, 2003

Sir:

In compliance with 37 CFR 1.56, Applicant(s) call(s) to the attention of the Patent and Trademark Office the reference listed on the attached PTO-1449.

A copy of the reference is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. <u>50-2866</u>.

Respectfully submitted, WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP

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Enclosures: PTO-1449; Reference (1)

INFORMATION			Atty. Docket No. 032015			Serial No. New Appln.			
DISCLOSURE STATEMENT		Applicant(s): Hirofumi WATATANI							
PTO-1449			Filing Date: October 16, 2003			Group Art Unit:			
				U.S. PATE	NT DOCUMENT	ΓS			
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